

Form PTO-1449 (Modified)

Atty Docket No.:  
G0131Serial No.:  
10/050,417

LIST OF PATENTS AND PUBLICATIONS  
FOR APPLICANT'S  
INFORMATION DISCLOSURE STATEMENT  
(Use several sheets if necessary)

Applicant: Khoi A. Phan, et al.

Filing Date:  
1/16/2002

Group: Unknown

RECEIVED  
JAN 16 2002  
U.S. PATENT AND TRADEMARK OFFICE

## REFERENCE DESIGNATION U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER			DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AA			COPY OF PAPERS ORIGINALLY FILED					
AB			-----					
AC								
AD								
AE								
AF								
AG								
AH								
AI								
AJ								

## FOREIGN PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
AK								

## OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

JKP	AM	"Understanding the DUV Resist Development Process Using A Develop Residue Monitoring Technique", C. Pike and J. Erhardt. Presented at Interface 1999: Microlithography Symposium, November 14-16, 1999.
JKP	AM	"An Investigation of Circular Resist Residue Defects in the Development of a 0.16μm Flash Process", J. Erhardt, K. Phan, and J. Cheng.
EXAMINER	J. K. Pike	DATE CONSIDERED 6/19/03

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.